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(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:
Takeo Nozaki

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Group Art Unit: N/A

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PATTERN INSPECTION DEVICE

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Dear Sir:

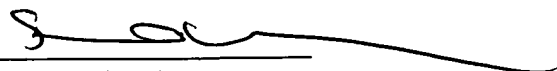
In accordance with the Manual of Patent Examining Procedures, Section 601.03, please change the mailing address for all correspondence in the above-identified patent application to:

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Dated: July 29, 2003

Respectfully submitted,

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